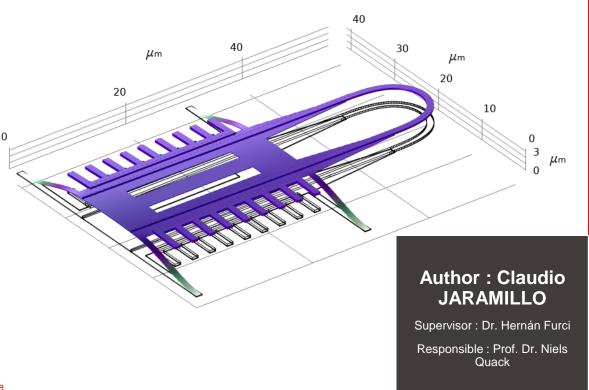


Surface: Total displacement (µm)



Optimization of Bistable Silicon Photonic MEMS Switch Architectures

■ École Polytechnique Fédérale de Lausanne – Q Lab

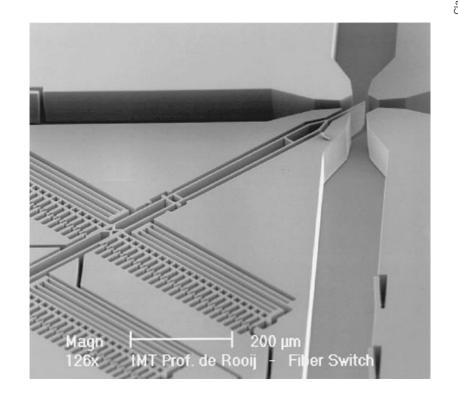
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- 5. Conclusions

1. Introduction

1. Introduction – Optical Switches

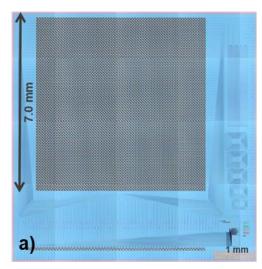
- Optical switch: device that switches optical signals between channels.
- Historically using mirrors.
- MEMS are advantageous for their integration capabilities, reliability, and low power consumption.
- Silicon photonic MEMS allows us to use well understood fabrication procedures.
- Exploiting mechanical properties of MEMS, instability under buckling creates 2 stable states: we have created a latching switch.

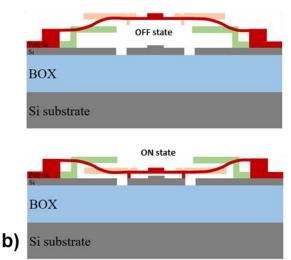


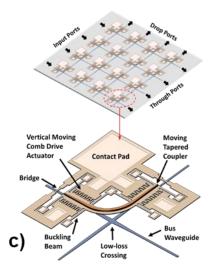


1.2 Introduction – Scope of the project

- "Silicon Photonic MEMS Switches have recently been shown to be an excellent contender for large-scale photonic integrated circuit switch matrices."
- We want to design and simulate optimized silicon MEMS switch architectures.







2. Current implementation

2.1 Current implementation – Original design

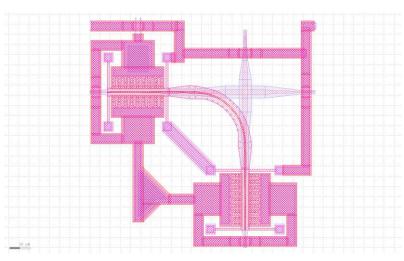
Output Ports

- The original design exhibits bi-axial stress. Leads to instabilities, and torsion.
- Footprint could be reduced.
- Any design must maintain the same optical losses.
- Low-loss crossing is untouched.

The matrix exists on 2 levels (top & bottom)

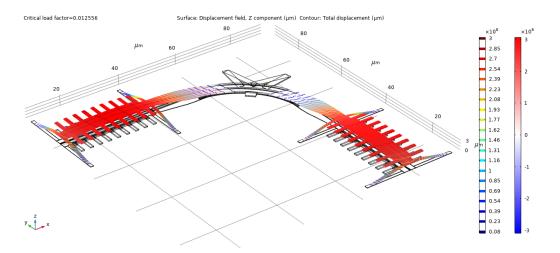
Strod Honor Ho





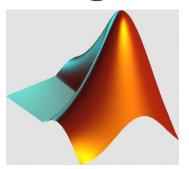
2.2 Current design – Optimization criteria

- Uniaxial stress only.
- Smaller footprint.
- Increase switching speed.
- Low losses.
- (optional) all inputs (resp. outputs) on the same side.



3. Design and development

3.1 Design and development - Methodology









- Geometry design on paper.
- 2. Implementation of specific elements using **MATLAB**.
- 3. Verification using KLayout & L-Edit.
- Assembly on L-Edit.
- 5. Simulation on COMSOL.

Design 1 : Linear Coupler

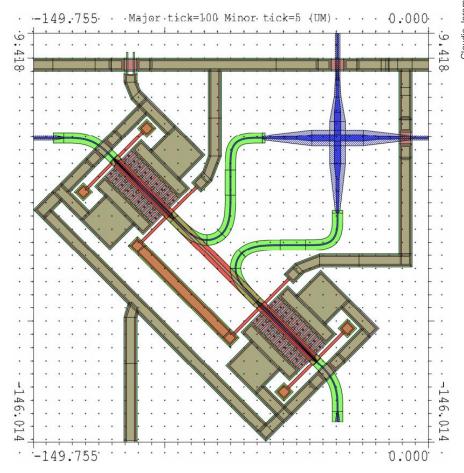
EPFL

3.2 Design and development –

Design 1

 Coupler principle : linear clamped-clamped beam.

- Bottom waveguide is deformed to comply with the geometry.
- We use a Sine-Circle-Sine curve matching strategy.
- Minimum radius of curvature is
 5 um (strip). Curvature is continuous.
- Estimated loss:
 - 0.06 dB/cell (BWG)
 - 0.48 dB/coupler

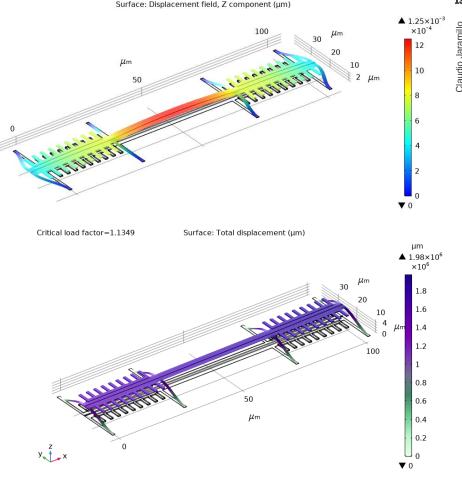


3.2 Design and development – Design 1 (cont'd)

 Compressive stress of 7.78 MPa is applied.
 Load of 0.27 nN applied.

y z x

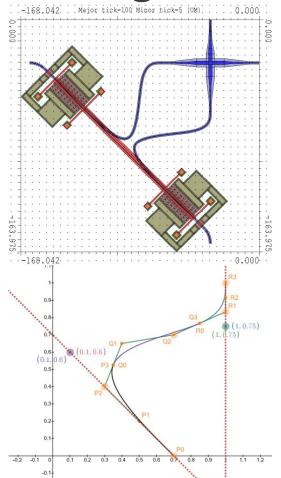
- Upwards buckling at critical load factor of λ=1.13.
- Stationary deflection is too small, because the load is small (less than 1 nm).



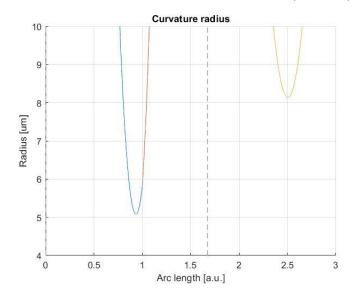
First buckling mode, critical load factor = 1.13

EPFL

3.2 Design and development – Design 1 alternative

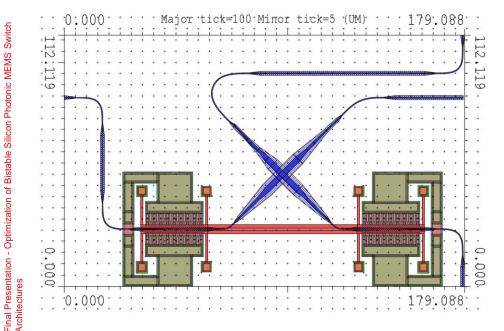


- Using 3rd order Bézier curves
 - The design respects all constraints.
 - However the entire path should be rib waveguides.
 - Coupler length is higher.
 - Estimated loss: 0.05 dB/cell (BWG).



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3.2 Design and development – Design 1 alternative (cont'd)

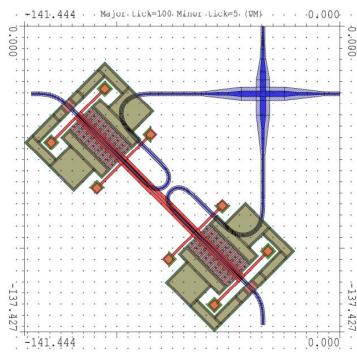


- We attempt to reduce the overall footprint by changing the orientation of the low-loss crossing.
- The coupler is pushed as close as possible to the crossing.
- Main problem : high optical losses.
- If we try to reduce the bends, we increase the footprint, and stagger the cells : bad design!

EPFL

3.2 Design and development - Design 1 conclusions

- Main limiting parameter is the crossing of both "lobes" on the bottom waveguide. Pushing the drive closer to the low-loss crossing creates an overlap in the lobes.
- A more compact design also interferes with the suspension and the row/column addressing.
- 3rd order Bézier curves provide an **elegant solution** to the problem.
- Main problems : footprint of low loss crossing, optical losses.

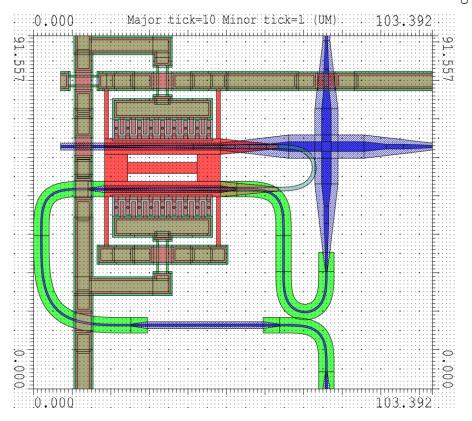


Linear design with lobes pushed close together

Design 2 : U-Turn coupler

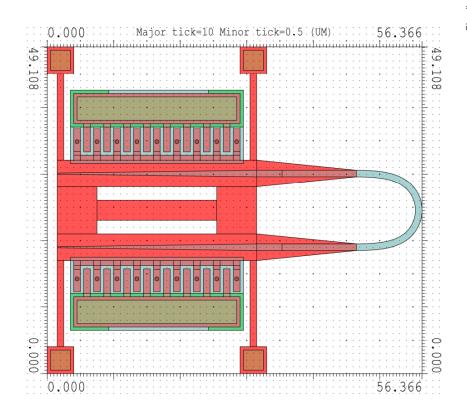
3.3 Design and development – Design 2

- Coupler principle : suspended U-Turn.
- Bottom waveguide is deformed using sine-circle sine methods.
- MEMS redesigned.
- Minimum radius of curvature is 5 um (strip).
- Estimated loss:
 - 0.13 dB/cell (BWG)
 - 0.52 dB/coupler



3.3 Design and development – Design 2 MEMS redesign

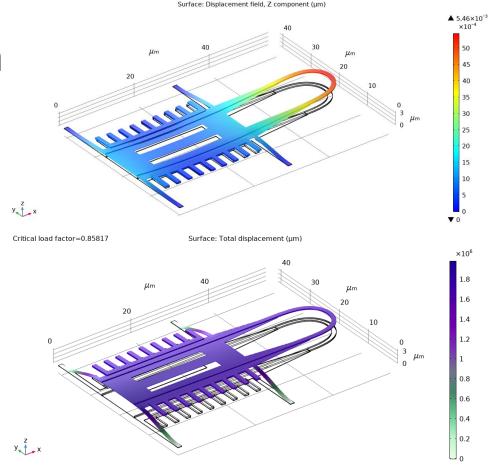
- We remove 2 comb drive actuators and join both inletoutlet together.
- Beam in the middle acts as anti-roll bar.
- The MEMS is already smaller than the crossing.
- Further mechanical simulations could reduce the MEMS mass.



U-Turn coupler with smallest possible radius.

3.2 Design and development – Design (cont'd)

- Compressive stress of 7.78 MPa is applied. Load of 0.27 nN applied.
- Upwards buckling at critical load factor of λ=0.86.
- Stationary deflection is too small.
- Deflection of 150 nm achieved for approx. 100 times the initial load.



First buckling mode, critical load factor = 0.86



3.2 Design and development – Design 2 conclusions

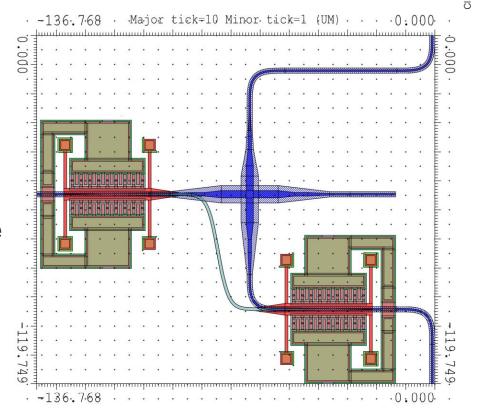
- The geometry is limited by the low-loss crossing.
- We redesigned the comb drives.
- Applied load is **not sufficient** to obtain the required deflection.
- Buckling mode behaviour as expected.
- Highly compact.
- Main problem : high optical losses.

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Design 3 : Sigmoid Coupler

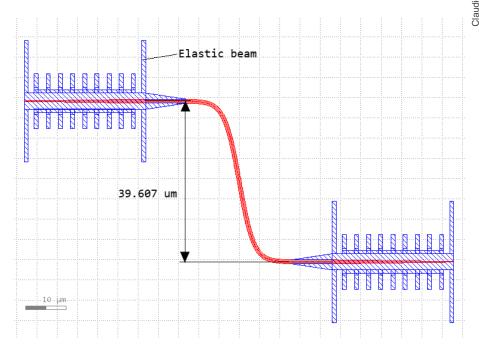
3.4 Design and development – Design 3

- Coupler principle : suspended logistic sigmoid function.
- Both waveguides are deformed using sine-circle sine methods.
- Minimum radius of curvature is 5 um (strip), obtained via parametrization.
- Estimated loss:
 - 0.08 dB/cell (BWG)
 - 0.54 dB/coupler



3.4 Design and development – Design 3 Coupler

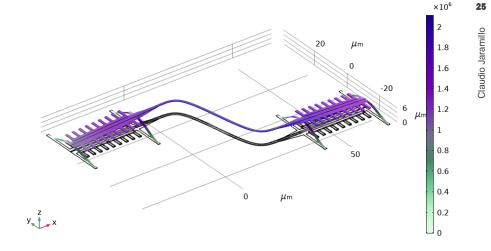
- The sigmoid height is limited by the low-loss crossing (again !).
- A smaller coupler would require a redesign of the BWG: tight turns, high losses.
- Mechanically compromised.



Sigmoid coupler with a height limited by the low-loss crossing.

3.2 Design and development - Design 3 simulations

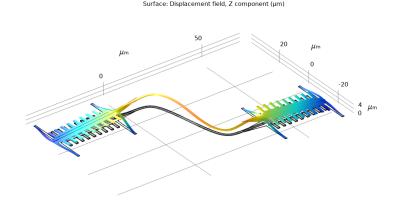
- Compressive stress of 7.78 MPa is applied. Load of 0.27 nN applied.
- Upwards buckling at critical load factor of $\lambda = 1.23$
- Stationary deflection shows that the design is mechanically unstable.



Surface: Total displacement (µm)

First buckling mode, critical load factor = 1.23

Critical load factor=1.2274





▼ -2.33×10⁻¹



Optimization of Bistable Silicon Photonic MEMS Switch

3.2 Design and development – Design 2 conclusions

- Elegant solution because of the parametrization capabilities.
- The geometry is limited by the low-loss crossing.
- MEMS is thin and long, therefore mechanically unstable, as expected and demonstrated by the FEM simulation.
- Design could be useful for a lower height (approx. 15 um).
- Main problems : high footprint, mechanically unstable MEMS.

4. Performance characteristics & Limitations



4.1 Performance characteristics – Summary

	Linear Design	U-Turn Design	Sigmoid Design
Estimated losses for the BWG [dB]	0.0595	0.1344	0.0845
Estimated losses for the coupler [dB]	0.0167	0.0496	0.0698

Table 1: Estimated optical losses for the 3 designs.

	Linear Coupler	U-Turn Coupler	Sigmoid Coupler
λ : 1st mode	1.135	0.858	1.227
λ : 2nd mode	1.152	1.016	1.281
λ : 3rd mode	1.954	1.118	1.653

Table 2: Summary of the critical load factors λ for each coupler, for the first 3 buckling mode shapes.



4.2 Limitations - Summary

Design size limitations

- Main limitation in the design is the low-loss crossing.
- For all 3 designs it is the limiting factor.
- But, the low-loss crossing cannot be miniaturized : current dimensions minimize cross-talk.

Performance limitations

- Main limitation in performance is the optical loss.
- If BWG's optical losses are in the range of the crossing, then the design is too lossy.
- All designs show high losses because the BWG needs to accommodate small MEMS, and a big LLC.

Final Presentation - Optimization of Bistable Silicon Photonic MEMS Switch Architectures

5. Conclusions

5. Conclusions

- The linear design as the lowest losses, and the simplest MEMS.
- The U-Turn design has the smallest MEMS, the smallest footprint, but the highest losses.
- It is important to keep in mind that the low-loss crossing is the limiting factor for all future work.
- These designs could be used for other projects.

	Pros	Cons
Linear design	Simple MEMS.Lowest optical losses.	Larger footprint.
U-Turn design	Most compact design.Smallest MEMS.	High optical losses.
Sigmoid design	 Low optical loss. Design could be used for other projects. 	 Mechanically unstable. Large footprint.

Thank you for your attention!

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